

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :
Fumio KONDO et al. :
Serial No. NEW : **Attn: APPLICATION BRANCH**
Filed February 27, 2004 : Attorney Docket No. 2004-0260

SUBSTRATE PROCESSING METHOD
(Rule 1.53(b) Continuation
of Serial No. 10/182,835,
Filed October 11, 2002)

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CLAIM OF PRIORITY UNDER 35 USC 119

Commissioner for Patents
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Sir:

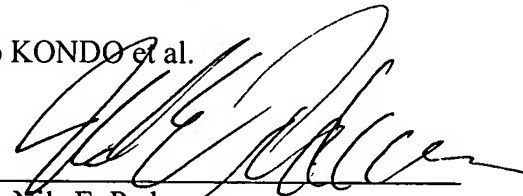
Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 2000-403889, filed December 4, 2000, as acknowledged in the Declaration of this application.

A certified copy of said Japanese Patent Application is of record in parent application Serial No. 10/182,835, filed October 11, 2002.

Respectfully submitted,

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By



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